Specifications (MA200)

Main body				
Focusing mechanism	Focusing nosepiece (Fixed stage) Coaxial coarse/fine adjustment knob (torque adjustable)			
, and the second	Coarse adjustment of 4.0mm per rotation, fine adjustment of 0.2mm per rotation			
Illumination	With flare prevention, Built in UV cut filter			
	Field diaphragm: dialing continuous variable (centerable), Aperture diaphragm: dialing continuous variable (centerable)			
	Filter: Double turret (ND16, ND4/GIF, NCB, Additional option available), Polarizing block (Selectable with or without 1/4 \(\Prime \) Plate)			
	Fluorescence filter blocks: B/G/V/BV, Built in 12V50W halogen lamp, C-HGFI HG Fiber Illuminator			
Light Distribution	Eyepiece tube/Back port: 100/0, 55/45			
Optics	CFI60 Optics			
Image orientation	Erect			
Observation method	Bright/Darkfield/Simple Polarizing/DIC/Epi-Fluorescence			
Revolving nosepieces	MA2-NUI5: Bright/Darkfield/DIC 5 position nosepiece, LV-NU5A: Motorized Bright/Darkfield/DIC 5 position nosepiece			
	D-NID6: Bright/Darkfield 6 position nosepiece (Intelligent), D-NI7: Brightfield 7 position nosepiece (Intelligent)			
Stage	MA2-SR Mechanical Stage (X/Y flexible handle)			
	Dimension: 295x215mm, Stroke: 50mmx50mm (with distance graduation), Standard accessory: ∮22 universal specimen holder (with sample clip)			
Trinocular eyepiece	Seidentopf, Interpupillary Distance Adjustment 50-75mm			
Power input	100-240V, 50-60Hz			
Electric power consumption	1.2A 50/60Hz			
Maximum electric power consumption	1.2A 75W			
Weight Approximately	26kg			
Option				
Intermediate magnification	Turret (1x, 1.5x, 2x), Status detection (Output magnification information to main unit)			
Scale	MA2-GR Grain Reticle (ASTM E112-63 grain sizing numbers 1 to 8), Grid Reticle(20 lines, 0.5mm)			
	MA2-MR Scale Reticle (compatible with 5-100x, Read in um, Dialing System)			

Specifications (MA100)

_ 1						
Optics	CFIco LU system					
Observation image	Upright reversed image					
Observation method	Brightfield and polarization (with MA P/A simple polarizer/analyzer set)					
Focusing	Focusing nosepiece (fixed stage)					
	Coaxial coarse/fine adjustment knob with 8.5-mm stroke (Coarse adjustment of 37.7mm per turn, fine adjustment of 0.2mm per turn)					
Nosepiece revolver	Brightfield 5-position nosepiece					
Stage	MA-SP Plain Stage: 170 x 230mm - Includes two stage inserts (1) clear acrylic stage insert with \$\phi\$30mm opening, (2) clear acrylic stage insert with crescent opening					
	(width 30mm) to allow clearance for rotation of high magnification objectives					
	Optional stage inserts: MA-SRSH1 Specimen Holder 1 with 15mm opening or MA-SH3 Specimen Holder 3 with 2mm to 32mm adjustable opening					
	Accepts Attachable Mechanical Stage TI-SM					
	TI-SM Attachable Mechanical Stage CH for use with Plain Stage: 126mm x 80mm stroke, handle can be attached on the right or left side of the plain stage					
	Optional Specimen Holders to fit Attachable Mechanical stage: MA-SH1 Specimen Holder 1 (φ15mm opening)					
	MA-SH2 Specimen Holder 2 (\$30mm opening), or C-HU Universal Holder (30mm to 65mm adjustable opening)					
	MA-SR Rectangular 3-plate Stage: 50 x 50 mm stroke (includes two stage inserts (\$\phi\$20mm and 40mm opening) and coaxial control handle on the right side					
	The 3-plate design allows entire top surface to move. Optional Stage inserts: MA-SRSH1 Specimen Holder 1 with (\$15mm opening or MA-SH3 Specimen Holder 3					
	with 2mm to 32mm adjustable opening					
Illuminator	Internal power supply 6V 30W Halogen Lamp (long-life type)					
	Condenser built-in (lever operated) \$25mm filter (includes NCB11 and ND4) can be inserted					
Binocular body with photo tube	Built-in Siedentopf binocular					
	45° inclination angle and 50 to 75-mm interpupillary adjustment; photo tube accepts ISO type CCTV/Digital Camera "C" mount adapters					
	Light path knob switches between 100% visual and 20% visual: 80% photo					
Electrical specification	Input: 100v/110v/120v, 220v/230v/240v 50-60Hz; Output: 1.5v to 6v; Max. power consumption: 96VA					
Lamp	6V 30W Halogen					
External dimensions	228 x 663 x 382 mm (W x D x H)					
Weight	Approx. 9kg					

Specifications and equipment are subject to change without any notice or obligation on the part of the manufacturer. October 2008 ©2006/2007/2008 NIKON CORPORATION

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TO ENSURE CORRECT USAGE, READ THE CORRESPONDING MANUALS CAREFULLY BEFORE USING THE EQUIPMENT.



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En







Nikon

Inverted Metallographic Microscopes MA200 MA100



Code No. 2CE-KGSH-1 Printed in Japan (0810-10) Am/M

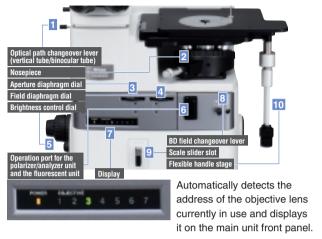
ECLIPSE MA200

New solution from Nikon: An ideal new microscope



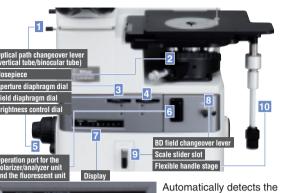
Front Operation

All controls are on the front of the instrument. Delivers ease-of-use by placing all important controls on the front.



Compact built-in design

Employs internal turrets that keep dust off the illumination filters, maintaining bright uniform illumination. Also, the power supply is built in to save space



Quick Status Check

The observation position of the objective lens and sample can be checked easily from the microscope's front panel.

Single-action operation

Analyzer/polarizer interlock mechanism

Links the attachment/release of the analyzer/polarizer.

Brightfield/Darkfield auto-aperture switching

The field stop and aperture stop automatically open when switched from brightfield to darkfield. When returning to brightfield observation, the previous field and aperture stop settings are reproduced.



Flash prevention mechanism

Reflection flashes when switching objective lenses are automatically prevented.

Box Structure

Smaller footprint than conventional models: Three times free spaces left!

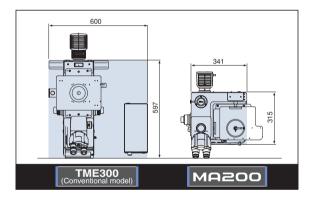
Improved durability thanks to the unique box structure.

Compact structure with a depth of 315 mm

A box shaped microscope, not only the width but also the depth is reduced dramatically: The foot print is only one-third of the conventional model!

High stability/durability

Vibration during high-power observation is reduced. Extremely high rigidity.

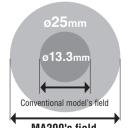


High Performance

Basic performance dramatically improved. Provides a more ergonomic and clear image observation.

Super-wide field of view

The ultra wide field of view eyepiece and with the combination of the newly developed 1x objective lens, a sample of 25mm diameter can be observed in an one field of view.



MA200's field

CFI60 optics

Nikon's world-class CFI60 optics, which provide clear, high-contrast brightfield images and darkfield images with three times the brightness of conventional models. New 1x and 40x objective lenses have been added to the line up.

Even Illumination

Improved uniformity of illumination delivers clear images, especially for digital imaging

Combine up to eight images with the stitching feature. Get natural lighting and no seams

Energy saving

The 50W halogen light source realizes the same brightness as the previous 100W light source with only about half the power consumption.

ECLIPSE MA100

Cost-effective microscopy, now simpler than ever



Introducing a durable, user-friendly Inverted Microscope with, superior image quality, a small footprint, and great cost performance

The ECLIPSE MA100 is a compact inverted microscope specially designed to meet the needs of reflected light observations requiring either brightfield or simple polarization illumination techniques. Its small foot-print, durable construction, simple operation, and superior Nikon optics, make it an ideal bench-top solution for: metallurgical samples, electronic components, failure analysis, materials science and quality control/quality assurance applications.

Stage

Stable control even with heavy samples A newly developed stage boasting superior durability

Nikon developed the new MA-SR Rectangular Stage especially for the MA100. The three-plate structure gives the microscope superior control and durability for observation of heavy samples, such as a grinder resin

mounted samples.



CFI60

Sharp, clear images using CFI60 optics

Nikon's proprietary CFI₆₀ System optics provide high Numerical aperture and longer working distance. CFI₆₀ LU optics deliver bright, high-resolution images with superior contrast. The built-in photo port, makes the MA100 ideally suited for digital image

capture. The built-in nosepiece turret mounts up to five objective lenses for a complete range of magnifications.



Aperture Diaphragm

Aperture diaphragm comes standard

The epi illuminator comes standard with a variable aperture diaphragm to control image contrast and depth of field.



Mirror

Identify objective magnification at a glance

The ECLIPSE MA100 incorporates a unique feature, a mirror to check under the stage. Now users can verify what objective lens

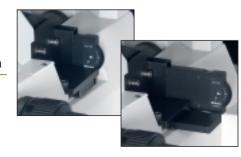
is being used as well as the position of the sample without having to look beneath the stage.



Polarizer/Analyzer

Simple polarization with a single-action polarizer/analyzer mechanism

The MA-P/A Pol Set makes reflected polarized light observation simple. It takes just a single action to slide the polarizer and analyzer in the light path. The polarizer can rotate 360° degrees, allowing users to set a polarization direction suited for the sample being observed. Samples typically observed under polarized light include: plastics, thin-films, metals, contaminants, chemicals, strain-tested materials, glasses and other materials etc.



4

ECLIPSE MA200/MA100

The ultimate imaging that only Nikon can offer.



Image Capture



DS-L2 camera control unit Stand-alone type

The built-in, high-definition, large 8.4-inch XGA LCD screen lets you view & discuss the sample without the need to look in the eyepieces.

Easily save/print data

Captured images can be saved to USB memory or a CF card. In addition to printing directly via a PictBridge-compatible printer, you can save data onto a server over a LAN.

Status Display MA200 only

The calibration data is automatically changed when the objective magnification is changed. This feature makes it easy to use the measurement function in the DS-L2. Quantitative illumination adjustment can be made manually by viewing the voltage value. This is crucial when acquiring the optimum settings for observation and image capture.



Image Analysis

DS-U2 camera control unit PC-controlled type

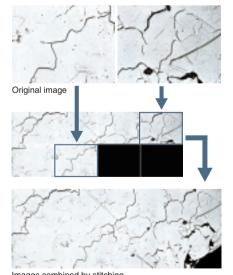
Imaging software NIS-Elements

DS-U2 and NIS-Elements allow the user to perform everything from basic image capture to the measurement, analysis, and management of captured images.

*See the NIS-Elements catalog for more information.

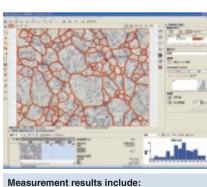
Stitching

Adjacent images can be put together to create an image with a wide field. It is now possible to capture even more vivid images due to the improved uniformity of the illumination.



Grain Size analysis Option

Detects and measures grains in one and two phase samples according to JIS G0551or ASTM E112-96/E1382-97 standards.



· G grain size · Grain size by area and/or intercepts Number of grains · Anisotropy index Other basic grain size statistics

Customizable measurement techniques provided: · Planimetric · Linear · Circular · Abrams

Status Display MA200 only

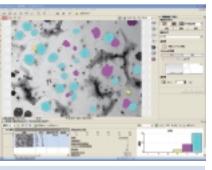
The calibration data is automatically changed when the objective magnification is changed. This feature makes the measurement function and other optional software modules such as grain sizing and cast iron analysis in the NIS-Elements easy to use.

Quantitative illumination adjustment which is crucial when acquiring the optimum settings for observation, image capture and especially large image stitching, can be made via PC control.



Cast Iron analysis Option

Detects, measures and classifies graphite content as well as ferrite content in graphitecorrected samples according to JIS G5502 or ASTM A247-06 standards.



Main applications

- · Graphite shape and size classification
- Graphite, Ferrite, Pearlite fractions Other basic iron analysis statistics
- Customizable functionality includes image masks, size restrictions and nodule shape classification.

Camera heads suited to specific applications

Cooled high-definition color camera head DS-Ri1

1.27-megapixel 2/3-inch color CCD



High-definition color camera head DS-Fi1 5-megapixel 2/3-inch color CCD



High-speed color camera head DS-2Mv 2-megapixel 1/1.8-inch color CCD



Accessories



Stage

The holder comes with a stage clip that enable sample rotation. This flexible handle stage delivers high durability needed to support heavy samples.

1 MA-2 SR Stage





MAZOO

Polarizing

Accessory required for simple polarizing observation.

1 MA2-PA Unit

2 MA2-UPA Unit*

3 MA2-λP λPlate *It is suitable for inspecting aluminium sample.



MA200

DIC

Accessory required for DIC observation.

1 MA2-PA Unit

2 L-DIHC DIC Prism (High Contrast)

3 L-DIC DIC Prism



MAZOO

Fluorescence

Accessory required for fluorescence observation.

1 MA2-FL FL G 2 MA2-FL FL B

3 MA2-FL FL BV

4 MA2-FL FL V

MAZOO



Diascopic Unit

Accessory required for transmitted illumination observation.

MA2-DP 100W Pillar



M0200

Digital Sight Series

A flexible system that enables various configurations consisting of a camera head and a control unit to suit the needs of each sample or application.



2 Acrylic Sample Holder (standard accessory/ ϕ 30mm aperture)

2 C-HU Universal Holder

3 MA-SH1 Specimen Holder 1

4 MA-SH2 Specimen Holder 2



MA 100

Stage+Holders C

Stage+Holders A

A simple fixed stage.

5 Acrylic Sample Holder (standard accessory/ crescent aperture)

MA-SH3 Specimen Holder 3 MA-SRSH1 Universal Specimen Holder

1 MA-SP Plain Stage

A triple-platform stage structure lets you use heavy samples.

MA-SR Rectangular Stage

2 Specimen Holder (standard accessory/ ϕ 20mm aperture)

MA-SH3 Specimen Holder 3 4 MA-SRSH1 Universal

Specimen Holder

5 Specimen Holder (standard accessory/ ϕ 40mm aperture)



Simple Polarizing

An accessory necessary for simple polarization observation.

1 MA-P/A Simple Polarizer



MA100

MA 100

The class of grain size in a sample can be easily

distinguished while observing its image.

1 MA100-EPRGS Grain Size Reticle

Grain Size Reticle



MA 100

Objective Lenses

CFI60 optics that provide uniform and clear images with both high NA and long working distance.

1 CFI L Plan EPI 1x, 40x



Туре	Power	Numerical aperture (NA)	Working distance (w.p.)(mm
CFI L Plan EPI	1x*	0.03	3.8
	2.5x	0.075	8.8
	40x	0.65	1.0
CFI LU Plan Fluor EPI	5x	0.15	23.5
	10x	0.30	17.5
	20x	0.45	4.5
	50x	0.80	1.0
	100x	0.90	1.0
CFI LU Plan EPI ELWD	20xA	0.40	13.0
	50xA	0.55	10.1
	100xA	0.80	3.5
CFI L Plan EPI SLWD	20x	0.35	24.0
	50x	0.45	17.0
	100x	0.70	6.5

Туре	Power	Numerical aperture (NA)	Working distance (W.D.)(mm
CFI LU Plan Apo EPI	100x	0.95	0.4
	150x	0.95	0.3
CFI LU Plan Fluor BD	5x	0.15	18.0
	10x	0.30	15.0
	20x	0.45	4.5
	50x	0.80	1.0
	100xA	0.90	1.0
CFI LU Plan BD ELWD	20xA	0.40	13.0
	50xA	0.55	9.8
	100xA	0.80	3.5
CFI LU Plan Apo BD	100x	0.90	0.51
	150x	0.90	0.4

"When using CFI L Plan EPI 1x with MA100 and MA200, the following acc are required. "MA2-PA Unit" when using with MA200 and "MA-P/A Simple Polarizing Set" when using with MA100. (Sales will start in January 2009)

Nosepiece & Magnification Module Enables communication of objective lens position,

magnification and intermediate magnification module information with the DS-L2 control unit and NIS-Elements image software.

MA2-MC Magnification Module

2 MA2-NUI5 Universal Intelligent Quintuple Nosepiece







MAZOO

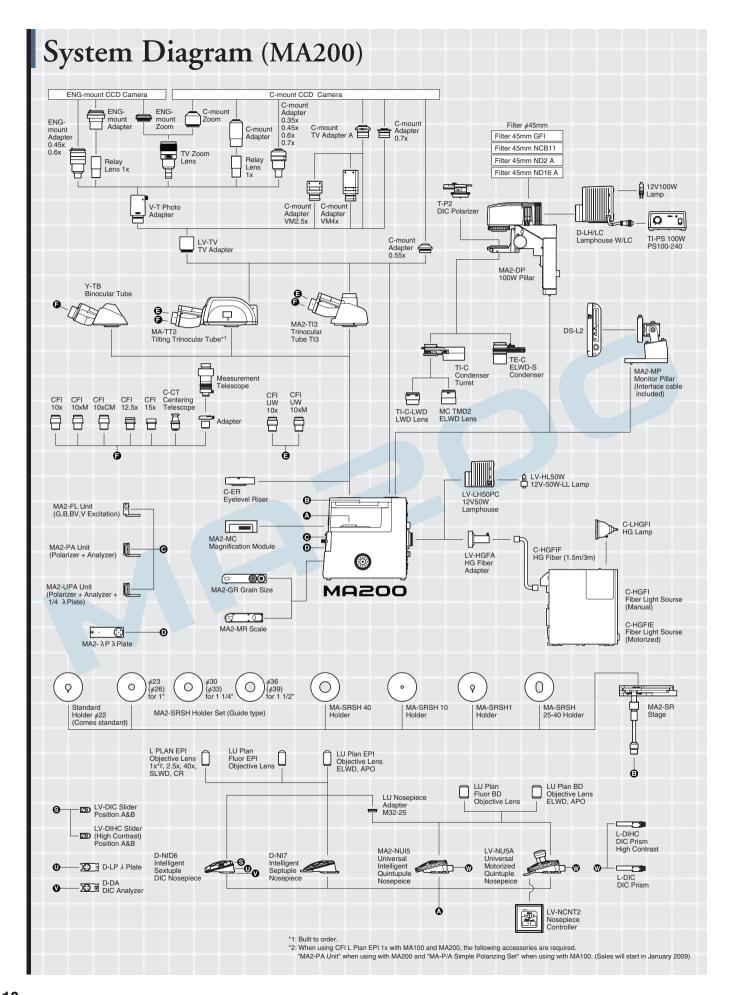
Grain Size Reticle & Scale

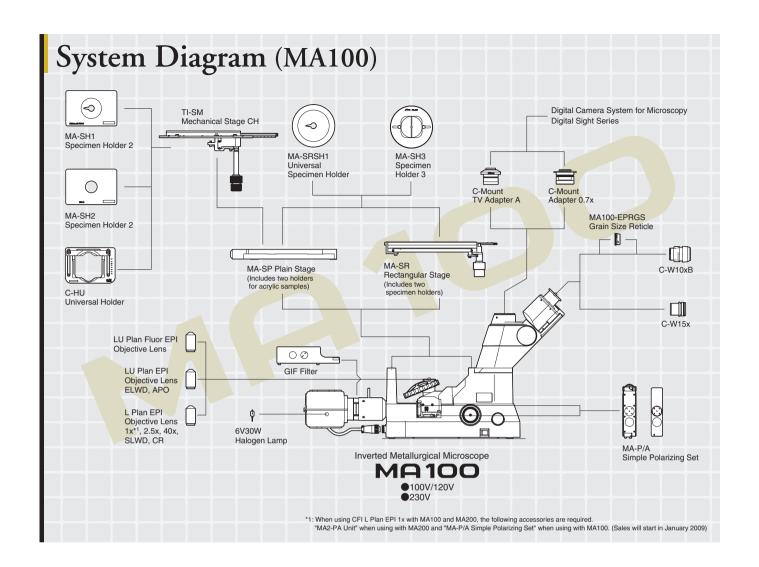
Overlays a pattern onto the observed image. MA2-GR Grain Size Reticle is used for grain size analysis which is compliant to JIS G0551 and ASTM E112 standards. The MA2-MR Scale is used for scale display for each objective magnification.

1 MA2-GR Grain Size Reticle 2 MA2-MR Scale

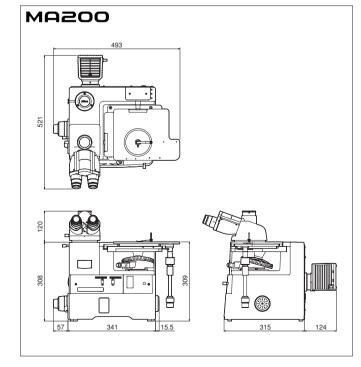


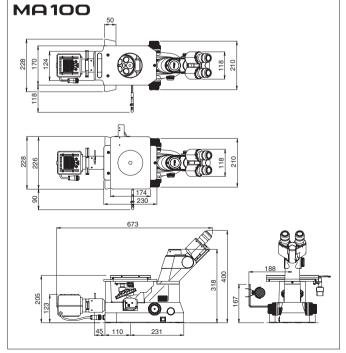
MAZOO





Dimensions





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